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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of: Chen et al.

Docket No.: TI-35022.2

Serial No.: 10/719,279

Art Unit: 2813

Filed: 11/21/03

Examiner: Chen, Jack S J

Title: Use Of Hafnium Silicon Oxynitride As The Cap Layer Of The Sidewall

Spacer

AMENDMENT UNDER 37 C.F.R. §1.116

February 7, 2005

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Dear Commissioner:

Do NOT enter CERTIFICATION OF FACSIMILE TRANSMISSION I hereby certify that the above correspondence is being transmitted by facsimile to the U.S. Patent and Trademark Office at 703-872-9306 on the date shown below.

In response to the Office Action, dated 10/18/2004, in the above-identified patent application, please make the following amendments. They are respectfully submitted as a full and complete response to that Action. Charge any required fees to the deposit account of Texas Instruments Incorporated, Account No. 20-0668.